

Ion source IBS-600



The device is designed to generate a linear flux of working gas ions with an energy of 300-2500 eV for a wide range of applications: ion cleaning, ion etching, ion polishing, ion modification, surface, assisting during spraying.

Parameter	Meaning
Beam shape	rectangular, hollow
Bundle size (L x W x T)	574x42x5 mm Length x Width x Thickness
Supply voltage	600-4000 V
Maximum beam current	1500 mA
Chamber working pressure range	0,001-10 Pa
Weight, no more, kg	11,1



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Basic dimensions

